

TRANSLATION FROM JAPANESE

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(54) Title of the Invention: **SEM type surface inspection apparatus**

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(57) Claims

- (1) SEM type surface inspection apparatus comprising: a scanning electron microscope; and a load-lock chamber situated adjacently to the lens body of said scanning

electron microscope and accommodating a cassette housing a multitude of wafers to be transported into said lens body.

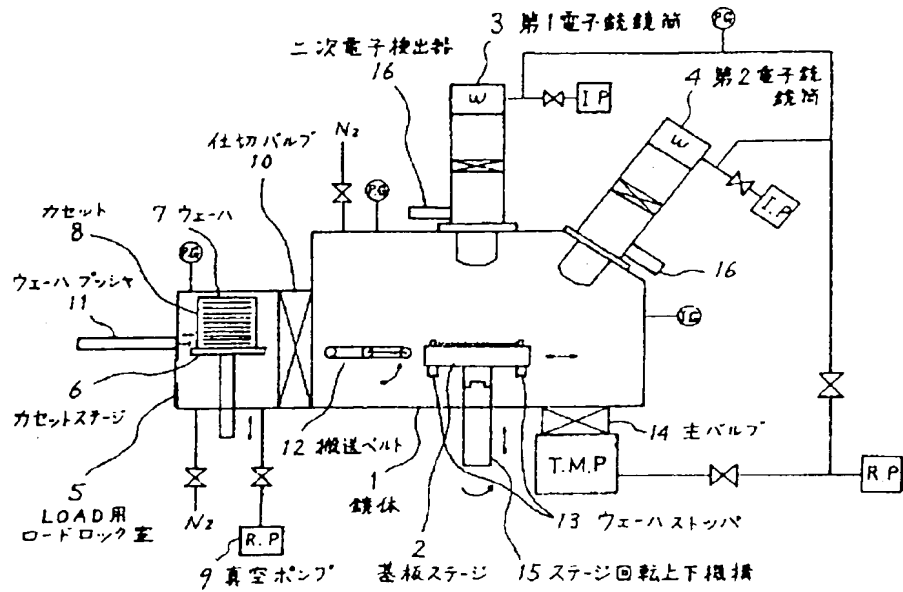
(2) SEM type surface inspection apparatus according to claim 1 wherein said scanning electron microscope mirror body comprises a plurality of electron gun lens barrels.

(3) SEM type surface inspection apparatus according to claim 2 wherein one of said electron gun lens barrels is an electron gun lens barrel for length measurement use.

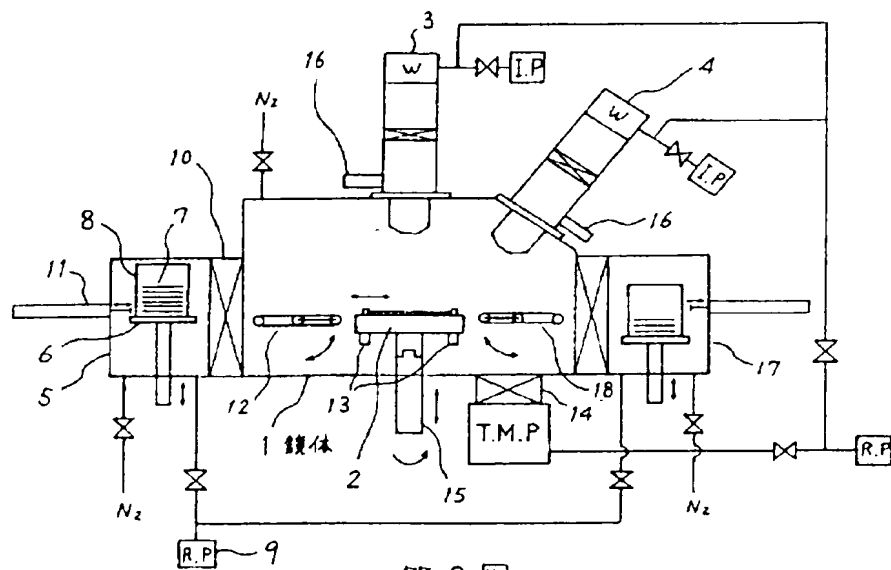
Brief Description of the Drawings

Fig. 1 is a construction diagram showing a first embodiment of the invention; and Fig. 2 is a construction diagram showing a second embodiment of the invention.

1: lens body (chamber); 2: substrate stage; 3: first electron gun lens barrel; 4: second electron gun lens barrel; 5: LOAD load-lock chamber; 6: cassette stage; 7: wafer; 8: cassette; 9: vacuum pump; 10: gate valve; 11: wafer pusher; 12: conveyor belt; 13: wafer stopper; 14: main valve; 15: stage rotating/elevating mechanism; 16: second electron detector; 17: UN LOAD load-lock chamber; 18: conveyor belt.



第1図



第2図

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⑩ 日本国特許庁(JP)

⑪ 実用新案出願公開

⑫ 公開実用新案公報(U)

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審査請求 未請求 (全 頁)

⑮ 考案の名称 SEM型の外観検査装置

⑯ 実 願 昭61-179904

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